

AMENDMENTS TO THE CLAIMS

1. (currently amended) A method of fabricating an optical semiconductor device, comprising the steps of:

forming a plurality of optical semiconductor elements on a semiconductor substrate;

forming a projection-like dummy portion in a center of a square at four corners of which said optical semiconductor elements are arranged; and

forming a buried layer by vapor phase epitaxy so as to bury a portion between said optical semiconductor elements and said dummy portion.

2. (original) A method according to claim 1, wherein said buried layer is formed by vapor phase epitaxy using one of a chloride-based source gas and a hydride-based source gas.